

U.S. Department of Commerce, Patent and Trademark Office	Atty Doc. No.	Application No.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	TNCR.181US0	09/639,495
	Applicant(s)	Confirmation No.
	Mehrdad Nikoonahad, et al.	Unknown
	Filing Date	Group
	August 14, 2000	2878

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AD						
	AE						
	AF						
	AG						
	AI						
	AJ						
	AD						
	AE						
	AF						
	AG						
	AK						
	AD						
	AE						
	AG						
	AH						
	AI						

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

R2	AQ	R. Pforr, et al., "In-Process Image Detecting Technique For Determination Of Overlay, And Image Quality For ASM-L Wafer Stepper", SPIE Vol. 1674 Optical/Laser Microlithography V (1992) pp. 594-608
Examiner	Date Considered 8/13/03	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.